

Inventor: Brenda D. Kraus et al.

Title: Atomic Layer Deposition Methods of Forming Conductive Metal Nitride Comprising Layers

Assignee: Micron Technology, Inc.

INFORMATION DISCLOSURE STATEMENT

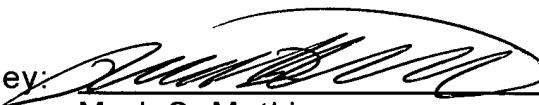
References -- See Attached Form PTO-1449

The attached form PTO-1449 is submitted in compliance with 37 CFR § 1.56. Copies of the cited art are included. No admission is made regarding whether all the submitted references are prior art.

Respectfully submitted,

Dated: 8-18-03

Attorney:


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Reg. No. 32,268

Form PTO-1449	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DOCKET NO. MI22-2310	SERIAL NO. Unknown
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)		APPLICANT: Brenda D. Kraus et al.	
		FILING DATE Filed Herewith	GROUP Unknown

U.S. PATENT DOCUMENTS

*Examiner's Initials		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	10/133,947		Vaartstra			04/25/2002
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AJ							
	AK							
	AL							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

	AM	Baghurst et al., <i>Microwave syntheses for superconducting ceramics</i> , 332 NATURE 11 (March 24, 1988).					
	AN	Kuo et al., <i>Microwave-assisted chemical vapor deposition process for synthesizing carbon nanotubes</i> ,					
	AO	J. VAC. SCI. TECHNOL., Vol. 19, No. 3, pp. 1030-1033 (May/June 2001).					
EXAMINER		DATE CONSIDERED					

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.